## **Claims**

We claim:

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1. A packaging device for semiconductor die, the packaging device comprising:

a substantially planar substrate having opposed major surfaces;
a conductive mounting pad located on one of the major surfaces;
a conductive connecting pad located on the other of the major surfaces; and
a conductive interconnecting element extending through the substrate and
electrically interconnecting the mounting pad and the connecting pad.

- 2. The packaging device of claim 1, in which the substrate comprises ceramic.
- 3. The packaging device of claim 1, in which the substrate comprises a material selected from epoxy laminate and silicon.
- 4. The packaging device of claim 1, in which the mounting pad and the connecting pad each comprise at least one of copper, silver, gold, nickel and tungsten.
- 5. The packaging device of claim 1, in which the conductive interconnecting element comprises tungsten.

- 6. The packaging device of claim 1, additionally comprising: a bonding pad located on the one of the major surfaces, an additional conductive connecting pad located on the other of the major surfaces, and
- an additional conductive interconnecting element extending through the substrate and electrically interconnecting the bonding pad and the additional connecting pad.
  - 7. The packaging device of claim 6, in which the substrate comprises ceramic.
  - 8. The packaging device of claim 6, in which the substrate comprises a material selected from epoxy laminate and silicon.
  - 9. The packaging device of claim 6, in which the mounting pad, the bonding pad and the connecting pads each comprise at least one of copper, silver, gold, nickel and tungsten.
  - 10. The packaging device of claim 6, in which the interconnecting element comprises tungsten.
    - 11. A semiconductor device, comprising:
    - a substantially planar substrate having opposed major surfaces;
    - a conductive mounting pad located on one of the major surfaces;
    - a conductive connecting pad located on the other of the major surfaces;
- a conductive interconnecting element extending through the substrate and electrically interconnecting the mounting pad and the connecting pad; and a semiconductor die attached to the mounting pad.

- 12. The semiconductor device of claim 11, in which the substrate comprises ceramic.
- 13. The semiconductor device of claim 11, in which the substrate comprises a material selected from epoxy laminate and silicon.
- 14. The semiconductor device of claim 11, in which the mounting pad and the connecting pad each comprise at least one of copper, silver, gold, nickel and tungsten.
- 15. The semiconductor device of claim 11, in which the conductive interconnecting element comprises tungsten.
- 16. The semiconductor device of claim 11, additionally comprising: a conductive bonding pad located on the one of the major surfaces; an additional conductive connecting pad located on the other of the major surfaces;
- an additional conductive interconnecting element extending through the substrate and electrically interconnecting the bonding pad and the additional connecting pad, and

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- a bonding wire extending between the semiconductor die and the bonding pad.
- 17. The semiconductor device of claim 16, additionally comprising an encapsulant encapsulating the semiconductor die and at least a portion of the major surface of the substrate on which the mounting pad is located.
- 18. The semiconductor device of claim 16, in which the substrate comprises a material selected from ceramic, epoxy laminate and silicon.

- 19. The semiconductor device of claim 16, in which the mounting pad, the bonding pad and the connecting pads each comprise at least one of copper, silver, gold, nickel and tungsten.
- 20. The semiconductor device of claim 16, in which the conductive interconnecting element comprises tungsten